

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Filed: December 16, 1999

For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR

jc564 U.S. PTO
09/461432
12/16/99


SECOND INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. §1.97 AND §1.98

Assistant Commissioner for Patents
Washington, D.C. 20231

December 16, 1999

Sir:

Pursuant to Applicants' duty of disclosure, enclosed
please find documents cited in an Office Action in connection
with a Japanese patent application corresponding to the above-
identified application. Further enclosed is a copy of a Form,
substantially equal to Form PTO-1449, listing the enclosed
documents.

The enclosed documents are being submitted concurrently
with the filing of the above-identified application.
Accordingly, it is respectfully submitted that the
requirements of 37 C.F.R. §1.97 are satisfied.

To the extent that the enclosed documents are not in
English, it is respectfully submitted that the requirements of
37 C.F.R. §1.98(a)(3) are satisfied by submitting abstracts of
various of the documents not in English, partial English
translations of various of the documents not in English, and
the following comments.

JP Hei 2-61064 corresponds to U.S. Patent No. 4,969,790,
and relates to a merry-go-round system.

No. JP Hei 1-310553 relates to a single chamber.

No. JP 1-251734 relates to a vacuum cassette.

No. JP Sho 62-44571 relates to an ion implantor.

No. JP Sho 62-50463 relates to a sputtering device; and
JP Hei 2-106037 relates to a single chamber device. JP No.
Sho 57-29577 relates to a sputtering device.

In "Semiconductor Equipment Association of Japan", a load lock chamber is defined.

In view of all the foregoing, it is respectfully submitted that all requirements of 37 C.F.R. §1.97 and §1.98 have been satisfied, in connection with the presently submitted documents. Accordingly, consideration of these documents, upon examination of the above-identified application, is respectfully requested.

To the extent necessary, please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to the Deposit Account No. 01-2135 (Case No. 503.30414C14) and please credit any excess fees to such Deposit Account.

Respectfully submitted,

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